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Description of reference numerals of the drawings

- 2: loading part
- 4: LCD module carrier box
- 6: first prechamber
- 8: first low vacuum pump
- 10, 32: gate valve
- 11: process chamber
- 12: outer chamber
- 14: inner chamber
- 15: through hole
- 16: high vacuum pump
- 20: gas supply source
- 22: ion gun
- 26: holder
- 28: power
- 30: second prechamber
- 34: second low vacuum pump

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Fig. 3

S2: loading a device

S4: forming cold plasma

S6: supplying ions

S8: injecting first ions

S10: rotating the device

S12: injecting second ions

S14: discharging the device

FIG. 1

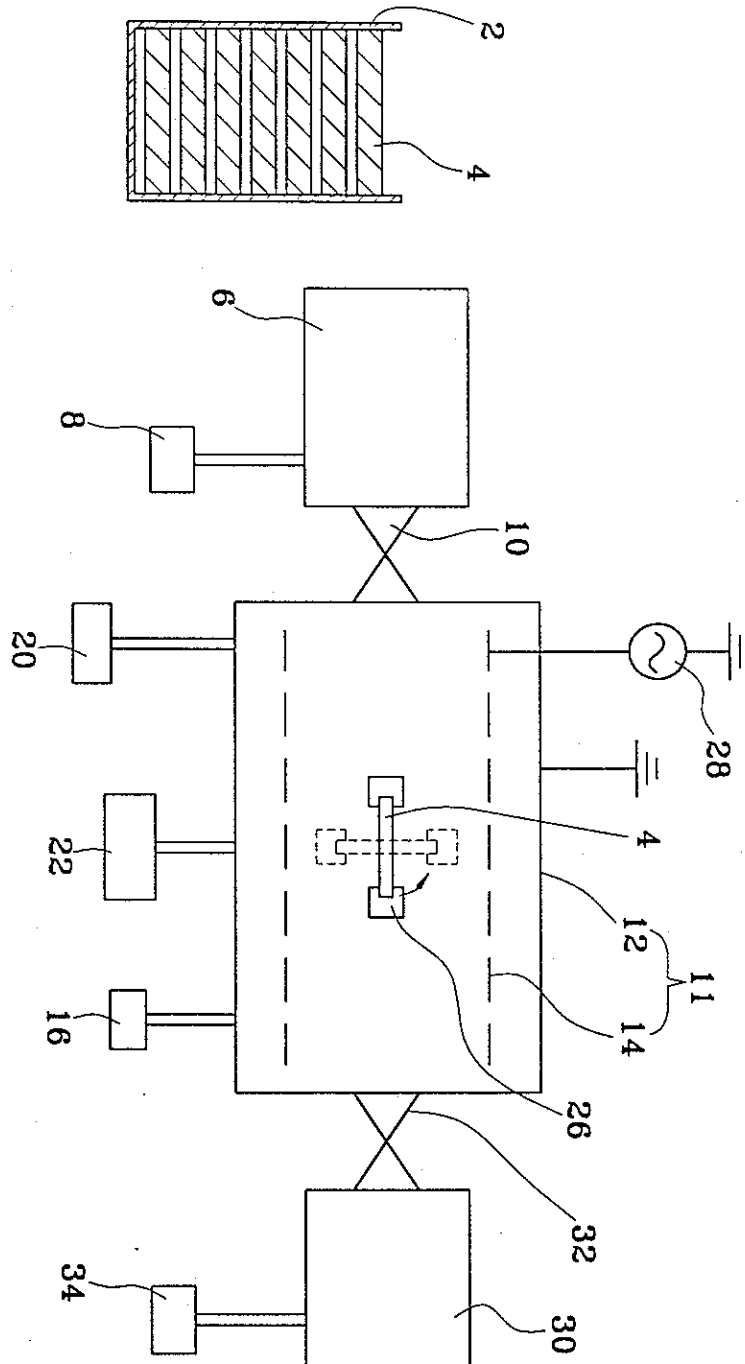


FIG.2

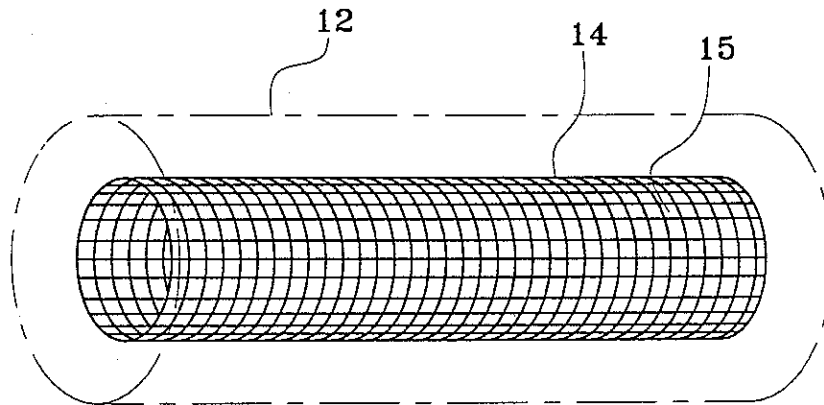


FIG.3

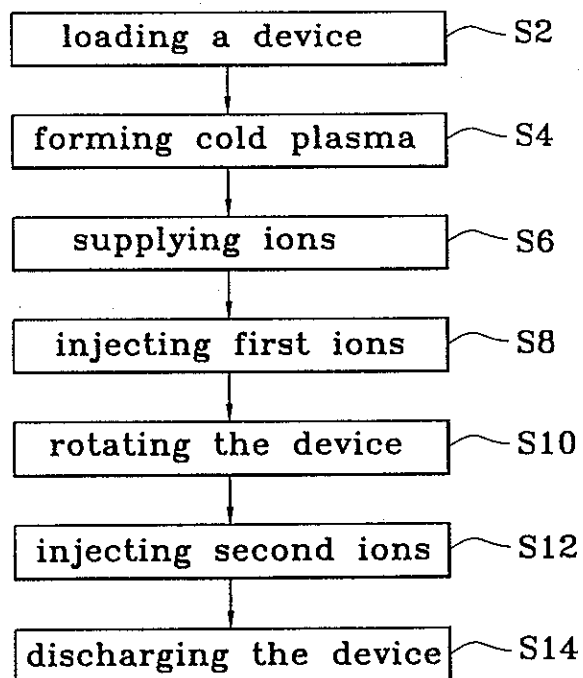


FIG.4a

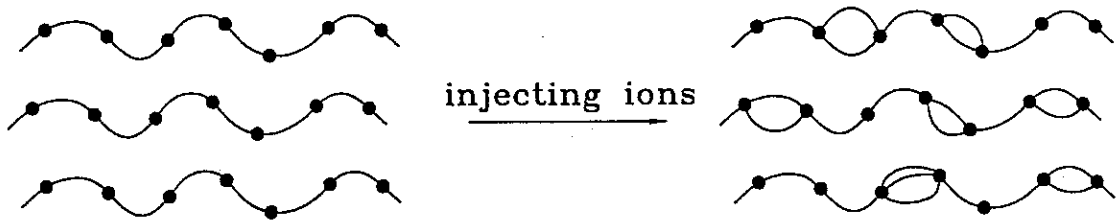


FIG.4b

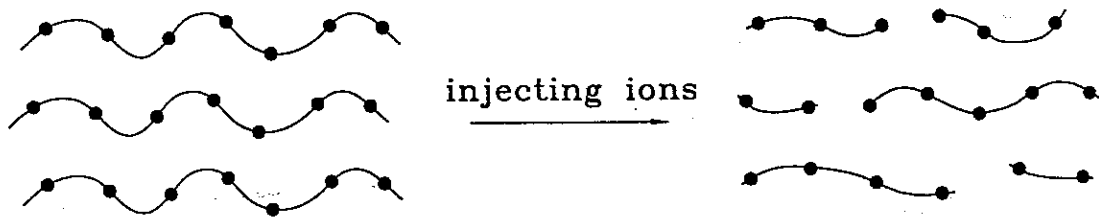


FIG.4c

